

IPW



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

First Named  
Inventor : Benjamin Y.H. Liu et al.

Appln. No. : 10/769,011

Filed : January 30, 2004

Group Art Unit: 1763

For : HIGH-PERFORMANCE AND MULTI-  
LIQUID-PRECURSOR  
VAPORIZATION IN  
SEMICONDUCTOR THIN FILM  
DEPOSITION

Examiner:

Docket No.: M419.12-0043

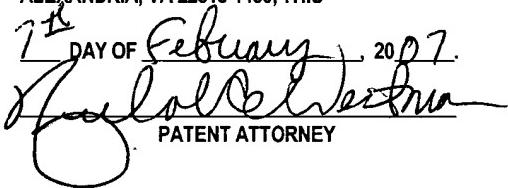
**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Official Action Mailed January 11, 2007,  
it is respectfully requested that the following amendments be made.

I HEREBY CERTIFY THAT THIS PAPER IS BEING  
SENT BY U.S. MAIL, FIRST CLASS, TO THE  
COMMISSIONER FOR PATENTS, P.O. BOX 1450,  
ALEXANDRIA, VA 22313-1450, THIS

7<sup>th</sup> DAY OF February, 2007.  
  
Patent Attorney